

	LASER INTERFEROMETER GRAVITATIONAL WAVE OBSERVATORY		E010099 -A- D
	SPECIFICATION		Drawing No    Rev.    Group
	Sheet 1    of    3		
<b>Substrate, Power Recycling Mirror, 40M RSE Experiment</b>			

AUTHOR:	CHECKED:	DATE	APPROVALS		
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			E010104	A	

### Applicable Documents

LIGO-D010101-A-D	Substrate, Power Recycling Mirror, 40M RSE Experiment
LIGO-E000409-A-D	Mirror Blank Material, Recycling Mirror, 40M
LIGO-D000268-A-D	Recycling Mirror Blank, 40M

### Requirements

#### Physical Configuration

According to LIGO- D010101	Substrate, Recycling Mirror, 40M RSE Experiment
Fabricate from LIGO-E000409	Mirror Blank Material, Recycling Mirror, 40M

#### Part and Serial Number

The Serial number shall be per D010101 and of the format:  
 PRM YY Where  
 YY        is incremental for each optic starting at 01

#### Registration Mark

Registration mark shall be etched, ground or sandblasted coincident with the registration mark drawn on the Blank within 5 mm. The arrow orientation used on the Blank will be preserved if possible or changes reported in detail. Reference LIGO-D000268, Recycling Mirror Blank.

#### Side and Bevel Polish

All sides and Bevels shall be polished from a five micrometer grit finish. These surfaces shall appear transparent with no gray, scuffs or scratches visible to the naked eye when viewed in normal room light against a black background.

**Substrate, Power Recycling Mirror, 40M RSE Experiment****Scratches and Point defects**

There shall be no scratches, sleeks or point defects within the central 10 mm  
The total area of scratches, sleeks and point defects within the central 30 mm diameter shall not exceed 500 square micrometers (width times length.)  
The total area of scratches outside the central 30 mm diameter shall not exceed 5,000 square micrometers.

**Minimum Point Defect**

Point defects which have a maximum dimension of 5 micrometers are disregarded.

**Inspection Method**

1. The surface is examined visually by two observers independently. The examination is done against a dark background using a three-bundle fiber-optic illumination system of at least 200 W total power. A 100% inspection of the surface is carried out. Pits and scratches down to 2 micrometers in width can be detected using this method of inspection. Any scratches that are detected will be measured using a calibrated eyepiece.
2. Further inspection will be done with a 6X eyeglass using the same illumination conditions, again with two observers. Sleeks down to 0.5 micrometers wide can be detected using this method. The surface will be scanned along one or two chords from center to edge, then at ten positions around the edge, and ten to fifteen positions near the center.
3. An inspection is then carried out with a dark field microscope with a similar sampling frequency as described in section 2.

**Surface Figure, measured over the central 30 mm diameter**

All specified quantities refer to the physical surface of the optic.

**Surface 1: Spherical, concave.**

Radius of curvature 348 meters concave  $\pm 20$  meters

Astigmatism:  $< 20$  nanometers (surface peak to valley)

**Surface 2: Nominally flat.**

Radius of curvature  $> \pm 5625$  meters

Astigmatism  $< 20$  nanometers (surface peak to valley)

## Substrate, Power Recycling Mirror, 40M RSE Experiment

### Surface Errors, Surface 1

The following root mean square standard deviation ( $\sigma_{\text{rms}}$ ) values are calculated from the phase maps which are to be provided with each optic.  $\sigma_{\text{rms}}$  is defined as the square root of the mean of the square of each pixel value. Known bad pixels are excluded from this calculation.

**Low Spatial Frequency Band  $< 32 \text{ cm}^{-1}$ :** The surface is measured using a commercial phase measurement interferometer and calibrated reference flat. With piston, tip, tilt, power (best fit spherical surface) and astigmatism removed over the central 30 mm diameter aperture:

$\sigma_{\text{rms}} < 5$  nanometers

**High Spatial Frequency Band:** Micro-roughness is measured with a commercial microscopic interferometer or surface profiler.

$\sigma_{\text{rms}} < 0.2$  nanometers

Measured at the following locations:

1. The center of the mirror substrate.
2. Four positions equally spaced along the circumference of a centered, 30 mm diameter circle.

Table 1 Certification Data Requirements

Specification	Test Method	Frequency of Inspection	Data Delivered
Physical Dimensions	Visual Inspection	100%	Certification
Side and Bevel Polish	Visual Inspection	100%	Certification
Scratches and Point defects	Visual Inspection	100%	Certification
Surface Figure	Interferometry	100%	Surface Map
Surface Errors – Low Spatial Frequency	Interferometry	100%	Surface Map
Surface Errors – High Spatial Frequency	High resolution Surface Map	100%	Certification

**Orientation:** For the purpose of full surface phase maps the substrate shall be oriented such that the point of minimum thickness shall be at the top center of the data.

**Format:** All Data shall be delivered according to Table 1. In addition to the hard copy an electronic data set of the phase maps shall be delivered in either ASCII or Vision.OPD format.